Paper No. 4

Date Mailed: November 27, 2001

Sheet 1 of 1

FORM 1449* INFORMATION DISCLOSURE STATEMENT IN AN APPLICATION (Use several sheets if necessary)

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Docket Number: AMDA.497PA	Application Number: 09/864,666
Applicant: Ring et al.	
Filing Date: 5/23/2001	Group Art Unit: 1746

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

RECEIVED FEB 07 2002 TC 1700

FOREIGN PATENT DOCUMENTS

	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES	TRANSLATION NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

L.T.N-E.	1999	K. Edinger, "Gas Assisted Etching of Copper with Focused Ion Beams", J. Vac. Sci. Technol., November/December 1999.

EXAMINER Lynette T. Umez-Eronini DATE CONSIDERED 5/20/2003

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form for next communication to the Applicant.

*Substitute Disclosure Statement Form (PTO-1449)